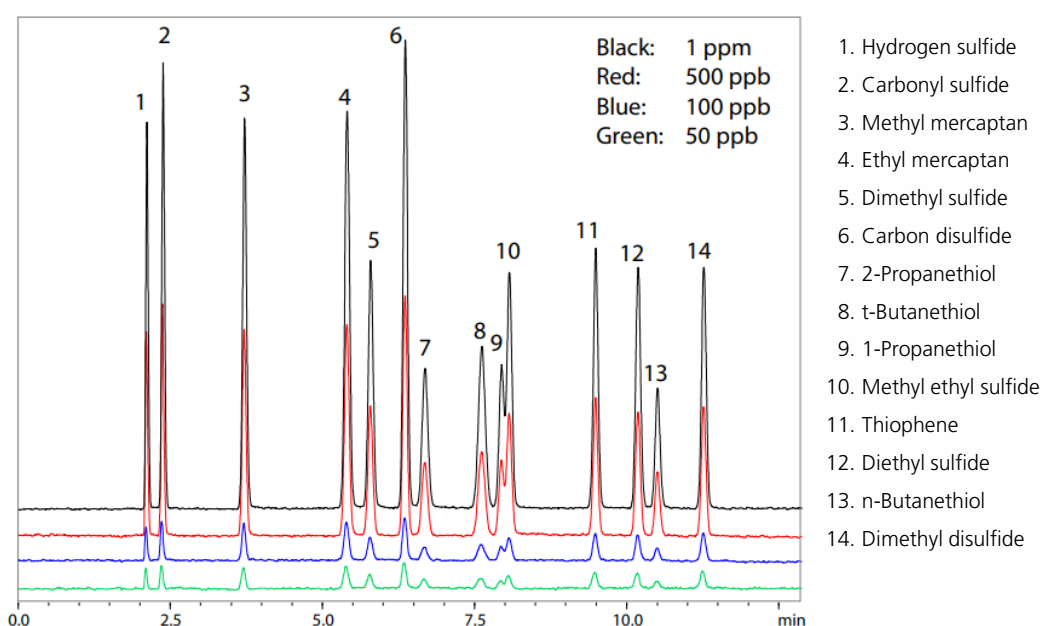


CoreFocus
Report
No.324

GC SCD Gas Sampler SH Series

SH-1
Analysis of Sulfur Compounds in Natural Gas According to ASTM D5504

Keywords: ASTM D5504, Sulfur compounds, Natural gas



Main Unit	: Nexis™ GC-2030
Valve	: 6-port Valve (Restek)
Sample Loop Volume	: 1 mL
Injector	: SPI
Column	: SH-1 (60 m x 0.53 mm I.D. df = 7 μm), P/N: 227-36108-02
Post Column	: Deactivated Fused Silica Tubing (0.3 m x 0.32 mm)
Detector	: SCD-2030
Injection Temp.	: 150 °C
Split Ratio	: 1:9 (10 % to column)

Carrier Gas	: He
Carrier Gas Control	: Constant Column Flow Mode (6.0 mL/min)
Column Temp.	: 30 °C(1.5 min) -10 °C/min - 200 °C (3 min)
SCD	
Interface Temp.	: 200 °C
Furnace Temp.	: 850 °C
H ₂ flow rate	: 100 mL/min
N ₂ flow rate	: 10 mL/min
O ₂ flow rate	: 12 mL/min
O ₃ flow rate	: 25 mL/min

Source : Application News G306 ([JP](#), [ENG](#))

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